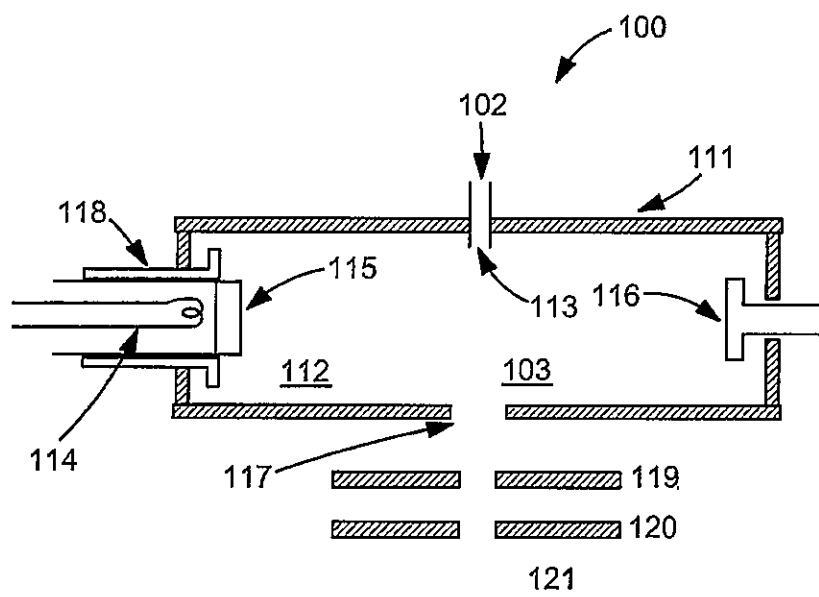




Schematic of an ion source apparatus

FIG. 1

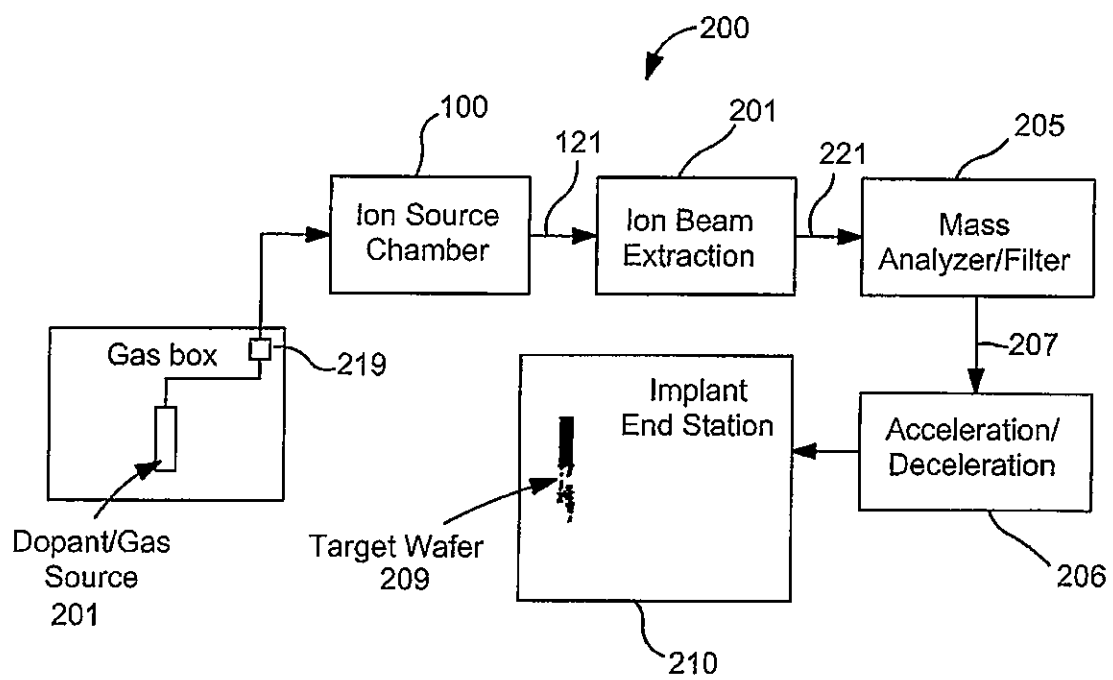


FIG. 2

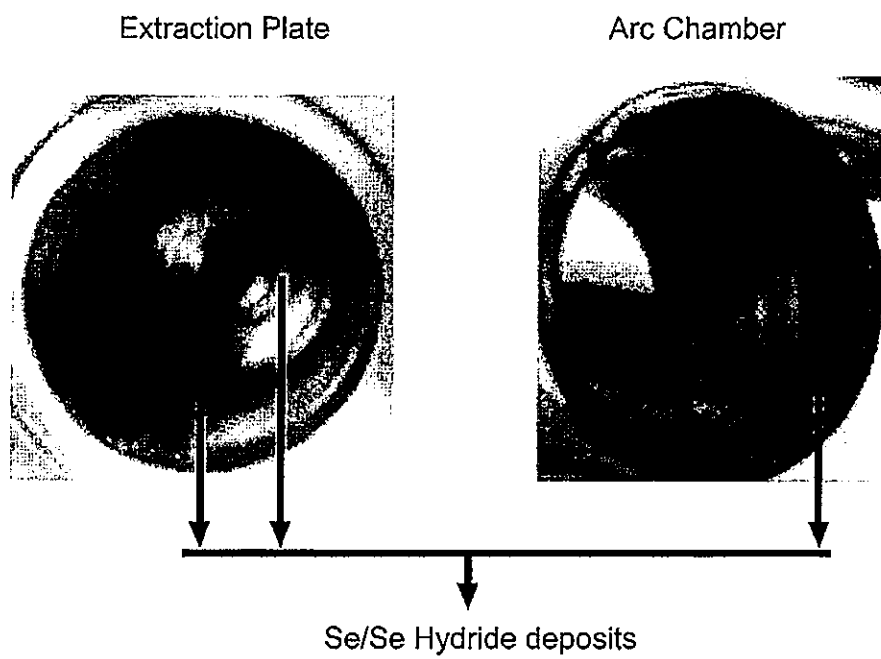
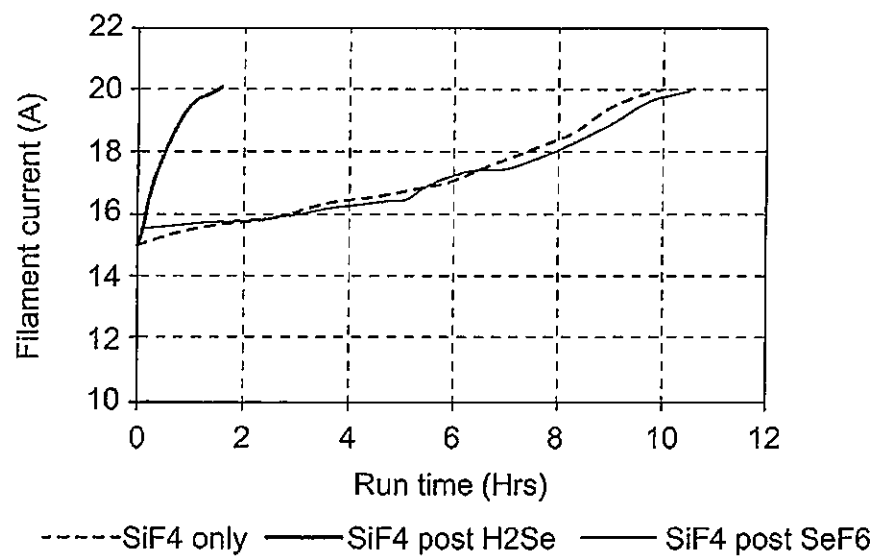


FIG. 3A

FIG. 3B

Deposits during H_2Se Implant



Filament current trend during SiF4 implant

FIG. 4

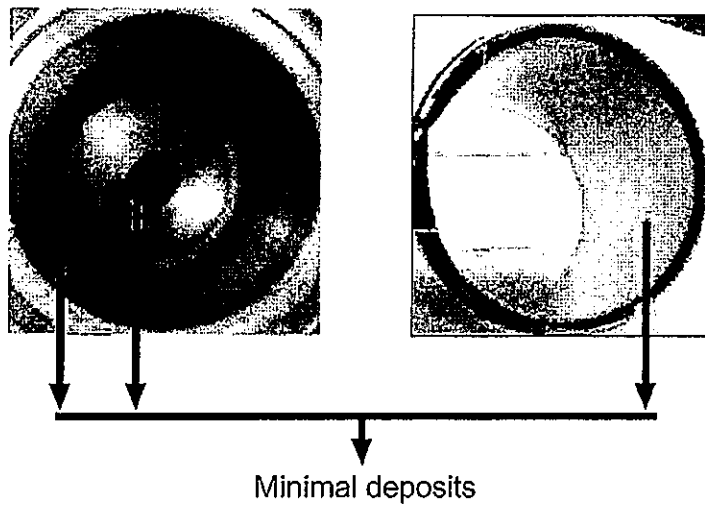


FIG. 5A

FIG. 5B

Deposits during enriched SeF_6 implant